

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.





FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)				ATTY DOCKET NO. <b>00862.023,57</b>		APPLICATION NO. <b>10/619,576</b>	
				APPLICANT <b>Hiroshi Watanabe et al.</b>			
				FILING DATE <b>SEP 16, 2003</b>			
				GROUP <b>N.Y.A. 1746</b>			

  

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
SC		5,520,744	05/28/96	Fujikawa et al.	134	11	
SC		4,746,397	05/24/88	Maeda et al.	156	637	
SC		5,331,987	07/26/94	Hayashi et al.	134	102.1	

  

FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
SC	JP	3-169013	07/22/91	Japan			Abstract
SC	JP	5-275412	10/22/93	Japan			Abstract
SC	JP	6-216101	08/05/94	Japan			Abstract
SC	JP	6-326073	11/25/94	Japan			Abstract
SC	JP	7-130699	05/19/95	Japan			Abstract

  

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)		
SC		Takeshi Hattori, <u>Silicon Wafer Surface Cleaning Technique New Edition</u> , pp. 450-463 (2001).

  

EXAMINER /Sharidan Carrillo/	DATE CONSIDERED 07/23/2006
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FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOK E NO/ 00862,023157 APPLICANT Hiroshi Watanab et al. FILING DATE July 16, 2003		APPLICATION NO. 10/619,576  GROUP N.Y.A. 1746	
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U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

  

FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
SC	JP	2002-16119	01/18/02	Japan			Abstract
SC	JP	2002-231688	09/16/02	Japan			Abstract
SC	JP	62-165939	07/22/87	Japan			Abstract
SC	JP	7-19765 B2	03/06/95	Japan			Abstract

  

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)		

  

EXAMINER /Sharidan Carrillo/	DATE CONSIDERED 07/23/2006
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Sheet 3 of 3

FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)				ATTY DOCKET NO. <b>00862.023157</b>		APPLICATION NO. <b>N.Y.A. 10/619576</b>	
				APPLICANT <b>Hiroshi Watanabe et al.</b>			
				FILING DATE <b>Herewith 7/16/03</b>		GROUP <b>N.Y.A. 1746</b>	

  

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	

  

FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT	
SC	JP	2000-277479	10/06/00	Japan			Abstract
SC	JP	10-64870	03/06/98	Japan			Abstract

  

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)		

  

EXAMINER <b>/Sharidan Carrillo/</b>	DATE CONSIDERED <b>07/23/2006</b>
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Sheet 1 of 1